

# IMN MacroNano®

Institut für Mikro- und Nanotechnologien

an example for effective  
interdisciplinary education and research

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# IMN MacroNano® of the TU Ilmenau

Electrical engineering

Computer science and engineering

Mechanical Engineering

Mathematics and natural science

Business and Media

Institut of Micro- und Nano-  
technologies

Institut for Energy Mobility and  
sustainability

Institut for Automotive and  
Production technique

Institut for Material Science

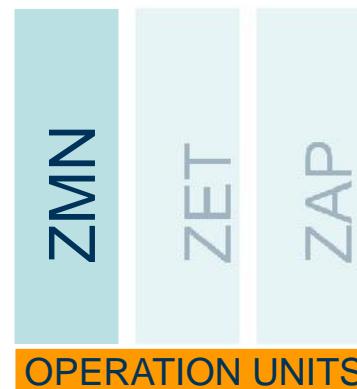
Institut for Media and Mobile  
Communication

Technological platform

Joint use of equipment

Joint re-financing of equipment

Professionell Administration



# Core facility: Center for Micro- and Nanotechnologies



Laboratory area: **2000 m<sup>2</sup>**

Including Cleanroom: **1180 m<sup>2</sup>**

Classes: **100-10.000 (5-7)**

*S1 – labs for biological applications*

*~300 scientists and technicians*





# History ZMN/IMN MacroNano®

**InQuoSens (Kooperation FSU und TU Ilmenau)**

Innovation center Quantumoptics und Sensorics

**DFG-core facility Mikro-Nano-Integration**

wider use of Infrastructure, financing in projects

**New clean room facilities**

Meitner building becomes part of TU Ilmenau

**DFG**



**Phase 2 ZIK MacroNano®**

Junior research group 3D-Nanostructuring



**Joint strategy plan of the  
39 members of IMN MacroNano®:**

**Founding of the IMN MacroNano®**

ZMN becomes operation unit of TU Ilmenau.

**MacroNano®**

ZENTREN FÜR  
INNOVATIONSKOMPETENZ  
**UNTERNEHMEN REGION**  
Die BMF-Innovationsinitiative  
Neue Länder

**ZIK ZMN / MacroNano**

Integration of 2 + 1 junior research groups and  
new scientific topics (Life Sciences, Peripherics)

**ZMN**

**Opening Zentrum of Micro- und Nanotechnologies (ZMN)**  
am 27.3.2002

2017

2013

2011

2009

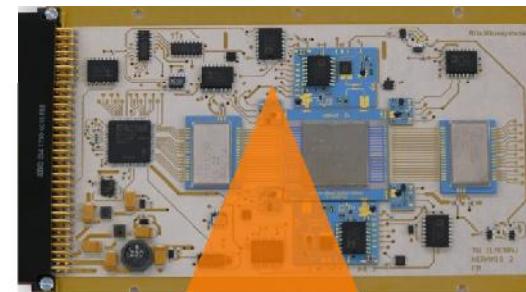
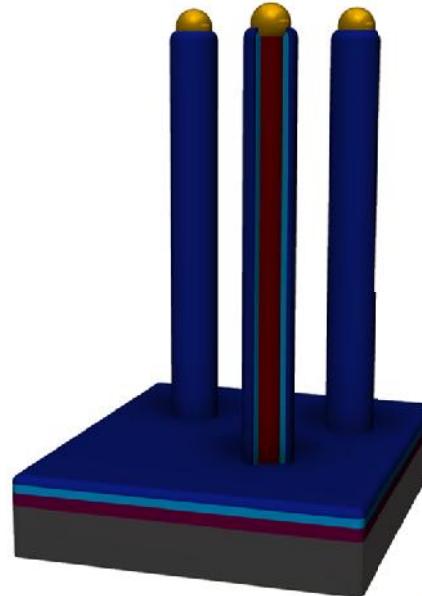
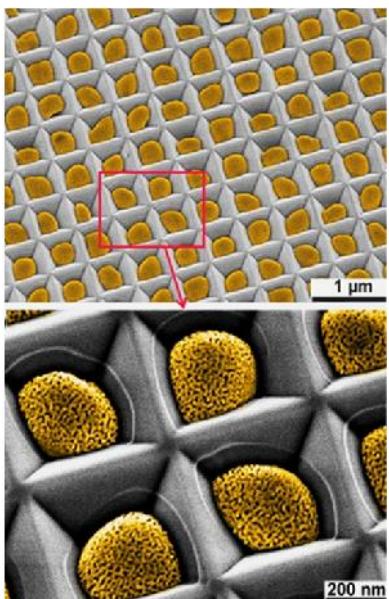
2006

2005

2002

# Research focus IMN MacroNano®

- Materials for Micro- und Nano-technologies
- Micro-Nano-Integration
- 3D Biosystems



Applications

System Integration

Device Realization

Process Technology

Basic Research

# Technology Lines

- Silicon-MEMS *cleanroom processing (6")*
- Polymer Electronics (*devices and solar cells*)
- LTCC-technology (*low temperature ceramics*)
- Group III-V materials (*MOCVD, MBE*)
- Nanostructures (*FIB and E-beam technology*)
- Laser-technology *for trimming and cutting of various materials*
- SMD-technology *and PCB-processing*
- Application lab (**S1**) *testing of complex biosensors*

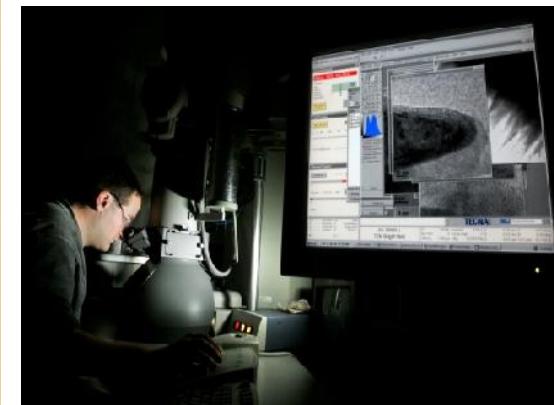


# Material Analysis

**Analytical systems down to atomic resolution**

- Electrical characterization
- Morphological, structural, and elemental material characterization including:
  - bulk properties
  - thin film characterization and depth profiling
  - surface analysis

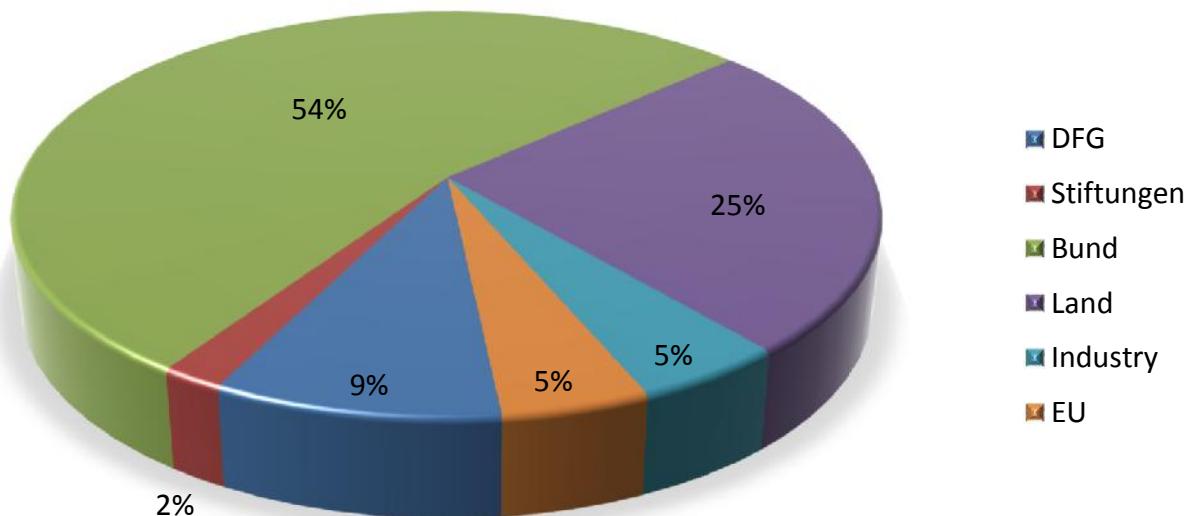
(e.g. by: TEM, spectroscopic ellipsometry, NMR, ESR, XRD, EDX, SEM, optical microscopy, PEEM, XPS, UPS, AES, RHEED, STM, AFM)



# Scientific Projects at IMN MacroNano®

- 50-70 Projects/year
- Total volume 2002 ... 2015 **84,16 Mio €**
- Overhead from DFG and BMBF 2010-2015: **3,56 Mio €**

Funding source  
2002 -2015

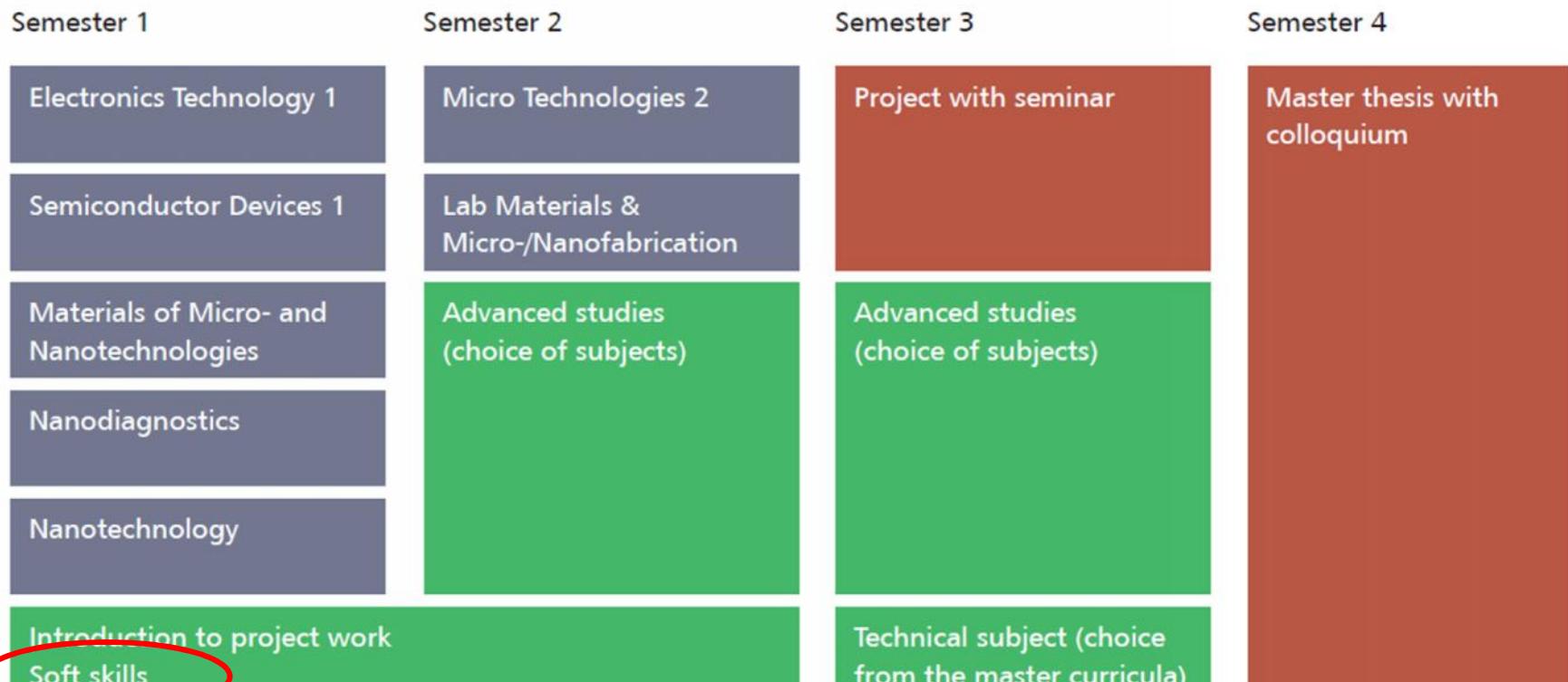




## education

- Master course „Micro- and Nanotechnologies“

# Master Program Overview



- Compulsory moduls
- Elective moduls
- Specialization

German Language Course  
if no German available



## education

- Master course „Micro- and Nanotechnologies“
- Available for teaching students with modern equipment
  - Lab courses
  - BA-thesis
  - MA-thesis
- PhD and Habilitation

# Possibilities for scientific cooperations



# Core facility micro-nano-Integration



**Phase I: 2013-2017**

**Phase II: ab Juli 2017**

aim:

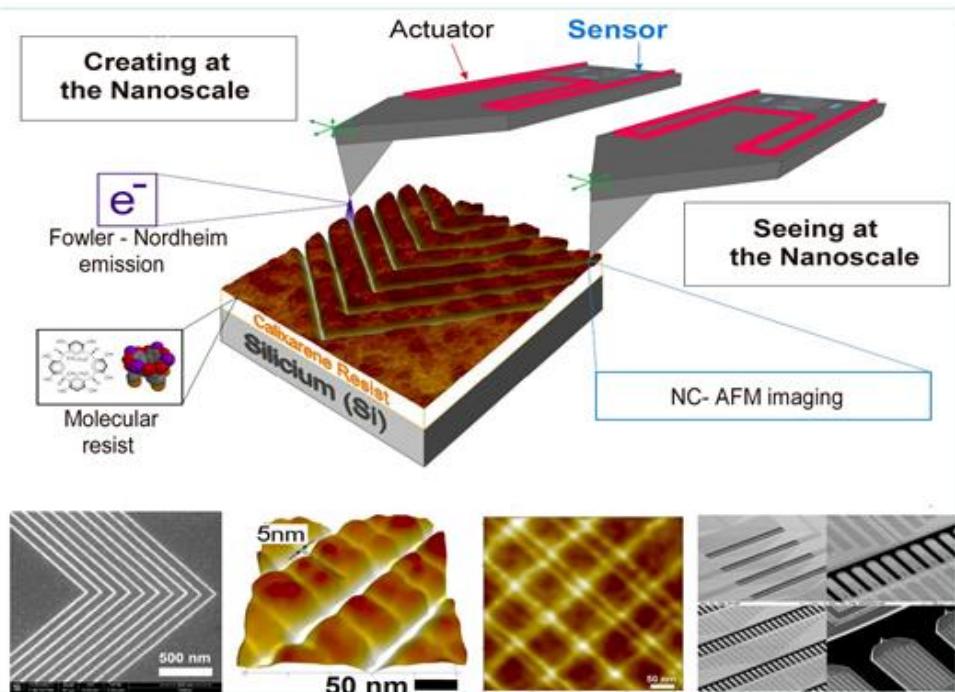
- Professional handling of tasks  
internal and external user
- Higher utilization of infrastructure
- Initiation of new research cooperations
- Technological support of projects
- Better settlement of efforts within  
DFG-Projects



Selected  
Research Highlights  
of  
**IMN MacroNano®**

# Single Nanometer Manufacturing for beyond CMOS devices

## "SNM" 2013-2017



### Scope:

- Extending the ability to scale down today's circuits to single nanometer using novel lithographic technologies and tools

### Tasks:

- SNM vision is to develop low cost, all dry, generic patterning technology for Single Nanometer Manufacturing for beyond CMOS devices
- Mask-less, "close-loop" lithography with high versatility and quick turnaround
- Nano Imprint Lithography for Low Cost Volume Manufacturing and Nanointegration
- SNM will enable new device concept based on 3D-nanostructuring

### Operating units:

- Coordinator: Prof. Ivo W. Rangelow,  
Micro- and Nano-electronic Systems

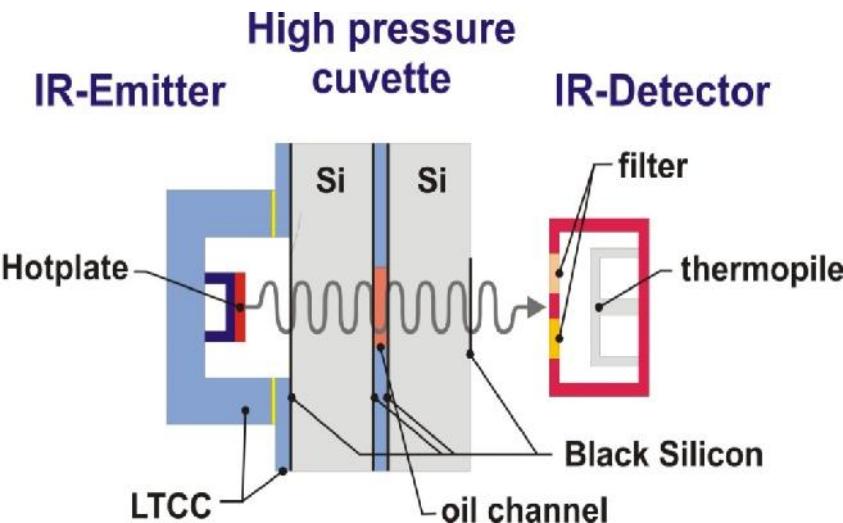
### Funded by:





Bundesministerium  
für Bildung  
und Forschung

# High Pressure IR-Measurement Cuvette



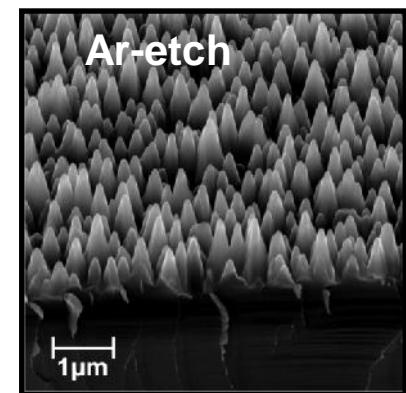
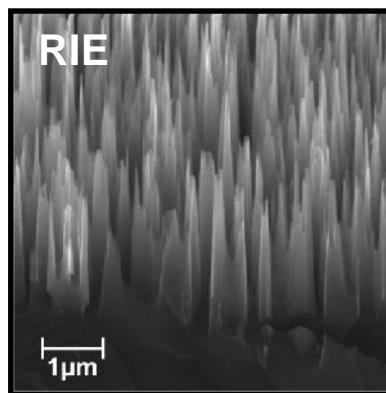
Oil cuvette made of silicon and LTCC

## Scope:

- Development of a high pressure cuvette for in-situ hydraulic oil monitoring for waste reduction
- Measurement principle: infrared spectroscopy

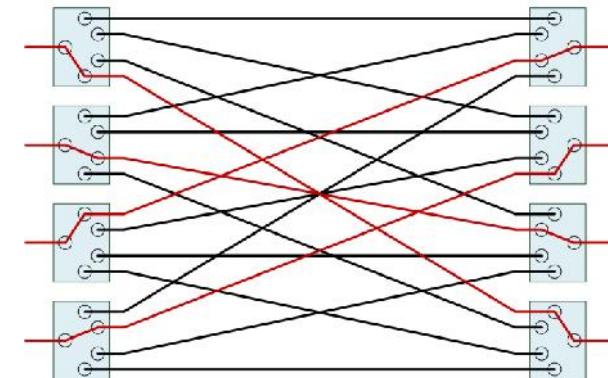
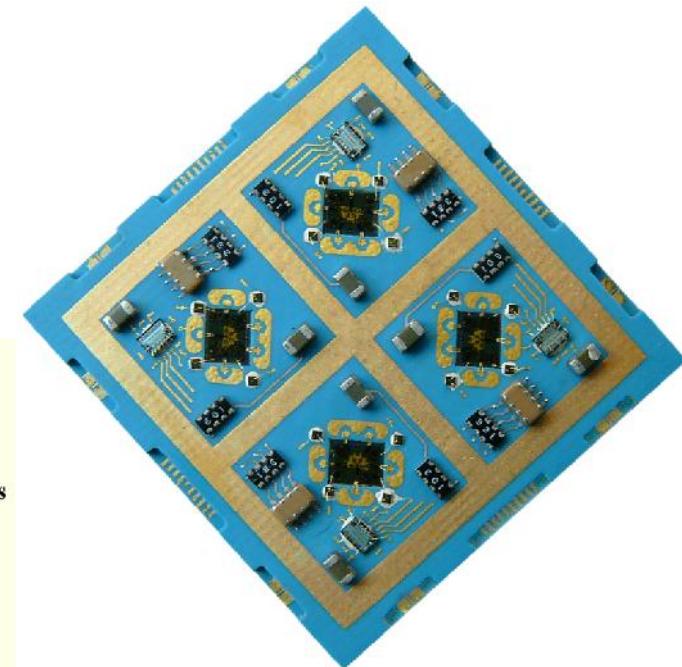
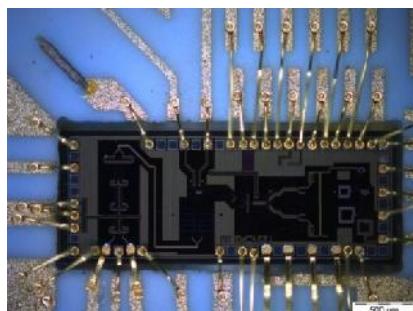
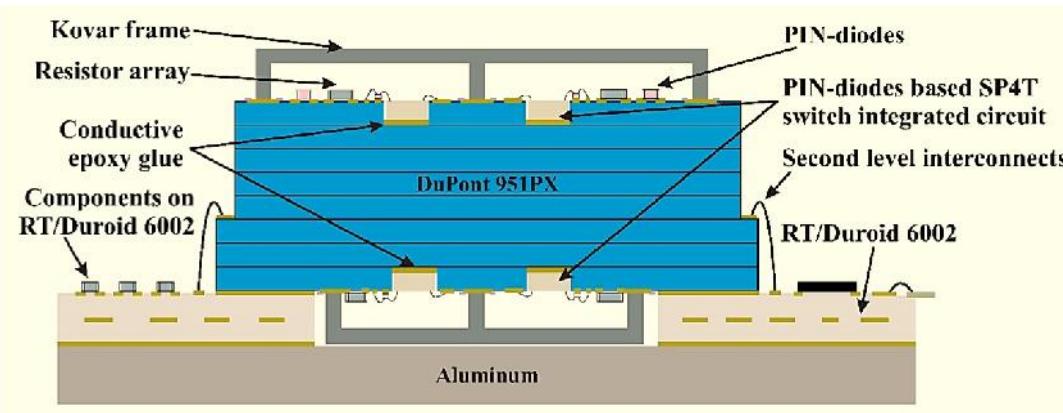
## Tasks:

- Improvement of infrared optical properties of components by surface nano-structuring
- Development of processes for silicon to LTCC bonding with high mechanical strength



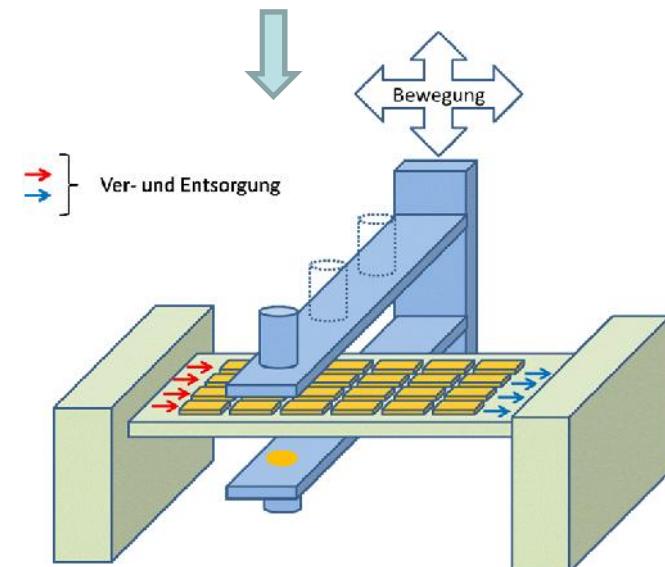
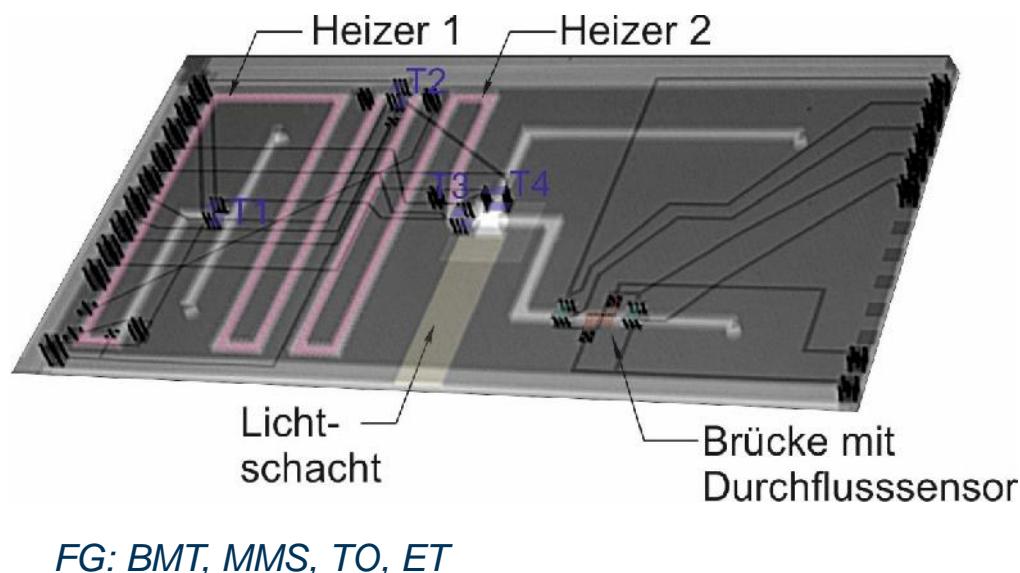
# LTCC Microwave and Harsh Environment Packaging

- Ka-band module: LTCC – PCB – FPGA
- Complete package w/ interfaces, digital control
- Fully space qualified



# Zeiss-Project: System for Automated Cell Cultivation

- Development of an automated workbench for cell cultivation
- High reproducibility of cell cultures under constant conditions
- Defined stress application (mechanical, optical, electrical, chemical)
- Multiple sensing principles



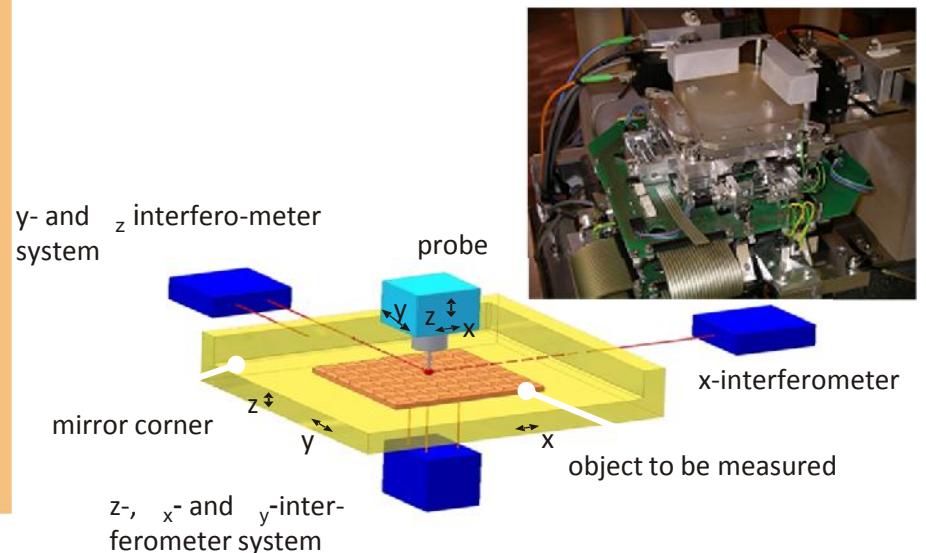
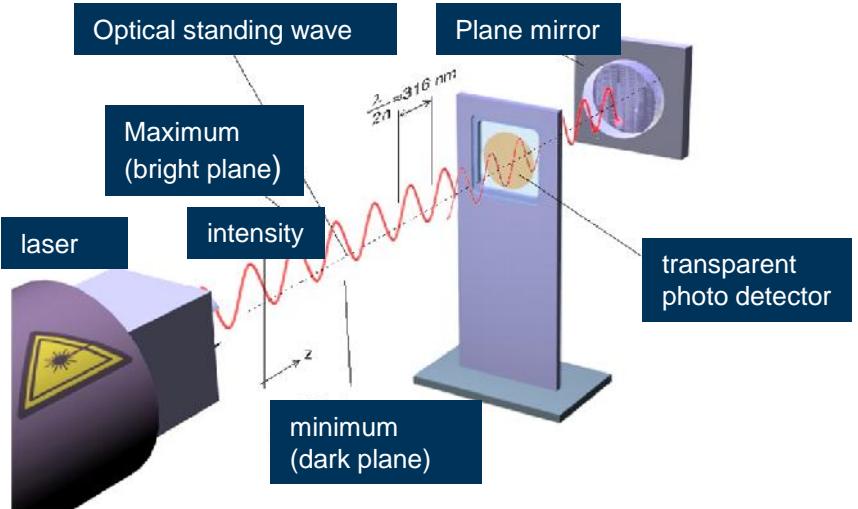
# Nanopositioning

## Nano Interferometer

- new ultra compact standing wave interferometer concept
- transparent photo detectors
- ultra-small volumina measurement

## Nanopositioning and Nanomeasuring Machine

- Collaborative Research Center
- Subnanometer resolution in large decimetre measuring volume



## Summary

- Exzellenz technological equipment
- + Professional organisation
- + Excellent possibilities for young researcher and students
- + Numerous third party funded projects in promising fields
- + Support by university direction

- 
- = interdisciplinary / interfacultative research
  - + with a broad range of topics

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= **important part of the profile of the TU Ilmenau**

## Contact:

Director:

Prof. Jens Müller

Technische Universität Ilmenau

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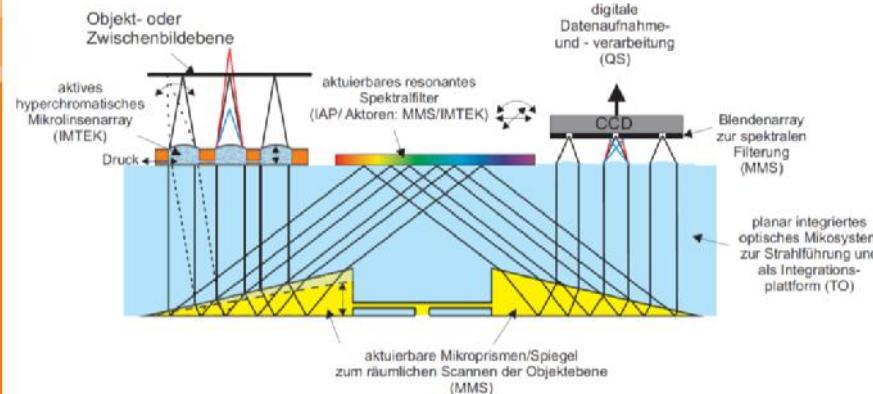


# Technische Universität Ilmenau

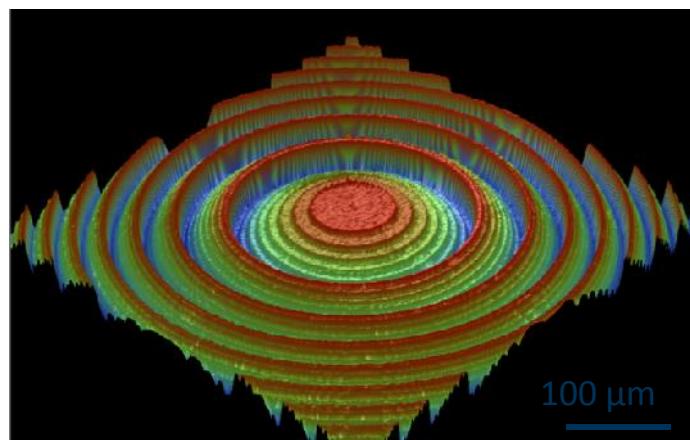


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# OpMiSen (2011-2014)



System concept



Diffractive microlens for hyperchromatic imaging systems

## Scope:

- Innovative optical systems for hyperspectral sensing and imaging based on active Microsystems

## Tasks:

- Concepts for integrated optical Microsystems for hyperspectral sensing
- Micromechanical actuators
- Algorithms for hyperspectral data recording and handling

## Operating unit:

- Technische Optik
- Mikromechanische Systeme
- Qualitätssicherung und industrielle Bildverarbeitung

## External partners:



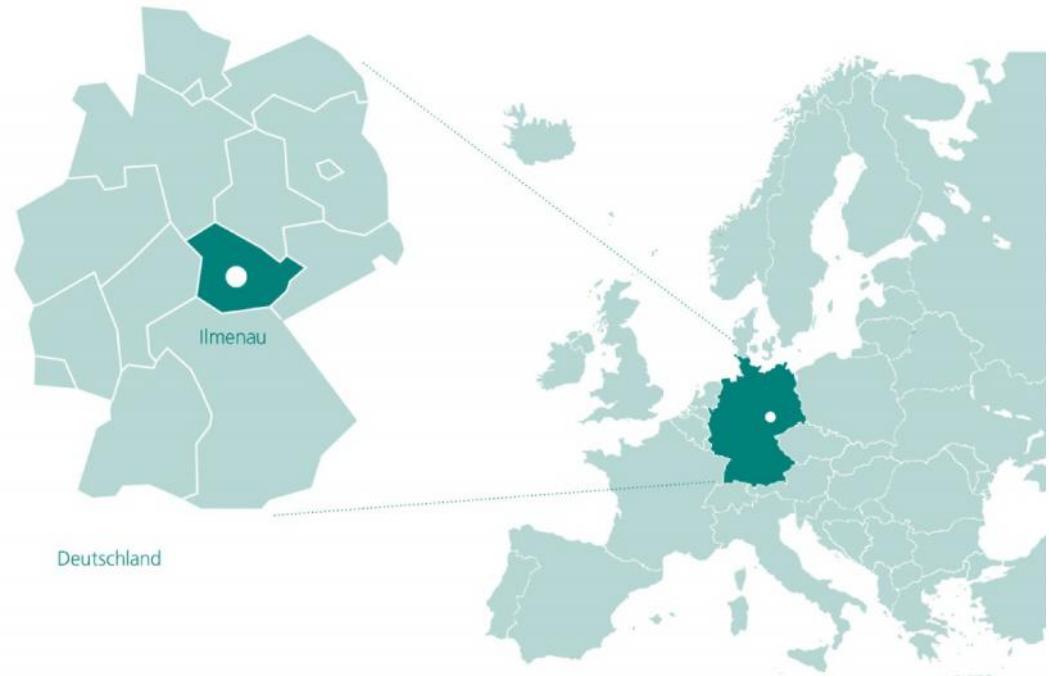
Bundesministerium  
für Bildung  
und Forschung

# equipment IMN MacroNano® (>450k€)

Gerät	Finanzierung	EFRE?	Jahr	Preis
FIB Auriga 60 Zeiss (Analyse)	Infrastrukturmaßnahme	x	04.12.2012	1.088.850,00 €
TEM TECNAI 2OS Twin Philips FEI	Erstausstattung		10.12.2001	1.001.800,49 €
FIB FEI Helios NanoLab	Berufungsmittel	x	13.04.2011	777.318,26 €
E-Beam-Writer Raith 150 Raith	Erstausstattung		29.07.2004	886.947,00 €
Cluster CS400 Ardenne	Infrastrukturmaßnahme	x	24.11.2010	1.143.349,67 €
MOCVD AIX200/AIX 200RF Aixtron	Erstausstattung		23.08.2004	1.530.978,14 €
Tempress LPCVD EQR531, Tempress Loadstation EQR531, PumpeR028	Erstausstattung		05.12.2001	653.416,09 €
AES Microlab 350 Thermo	Erstausstattung		29.03.2005	772.722,40 €
MBE/PECVD UMS500Balzers	Projektmittel		20.06.1995	1.177.968,77 €
Wachstumsmodul Omicron	Erstausstattung		30.11.2001	1.320.420,30 €
3D-Pikosekunden-Laserablationsanlage	Berufungsmittel		30.06.2015	648.817,69 €
DRIE - Estrelas	Infrastrukturmaßnahme	x	26.09.2014	507.211,77 €
Ultrapräzisionsbearbeitungszentrum Micro-Gantry nano4x Kugler incl. Drehzahlmesser	Berufungsmittel	x	08.06.2007	703.778,86 €
Laser Scanning Microscop + Rechner Olympus IX 81	Projektmittel		21.02.2008	472.538,95 €
XPS Analytik SAGE HR 150	Infrastrukturmaßnahme	x	26.11.2013	490.038,22 €
Diffaktometer D8 µXRD	Projektmittel		13.06.2017	490.451,07 €
REM Gemini SEM 500	Berufungsmittel		04.08.2016	543.532,50 €

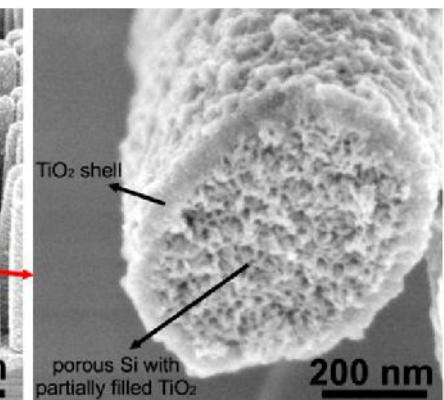
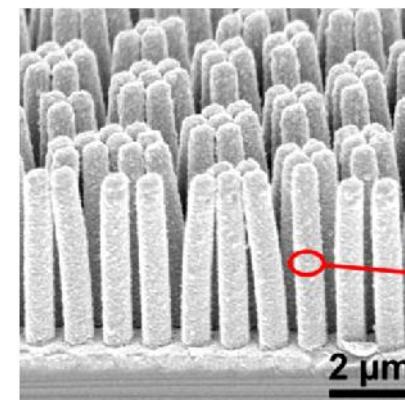
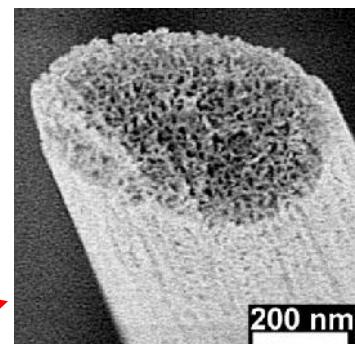
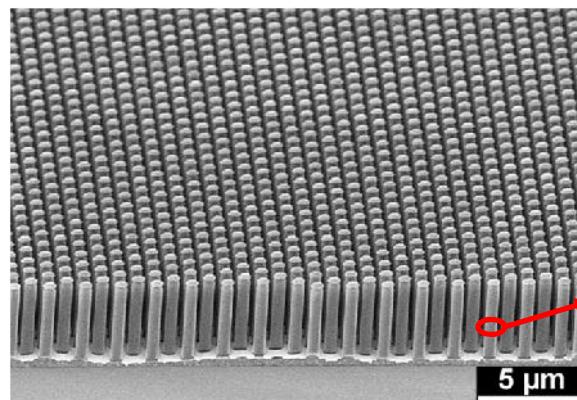
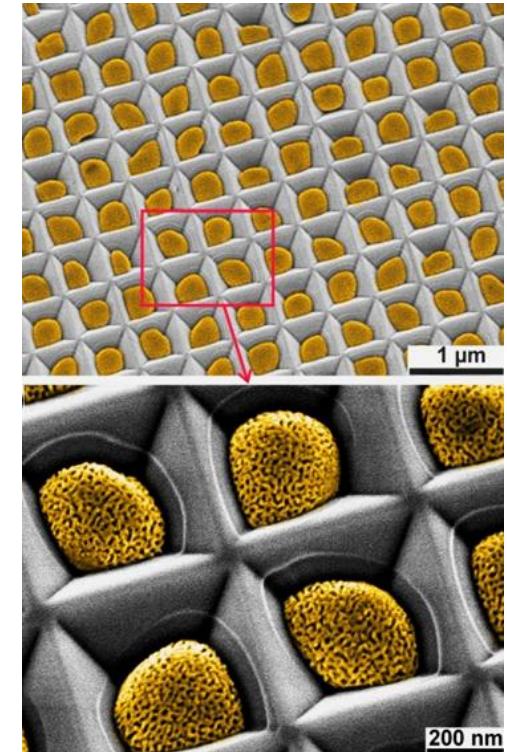
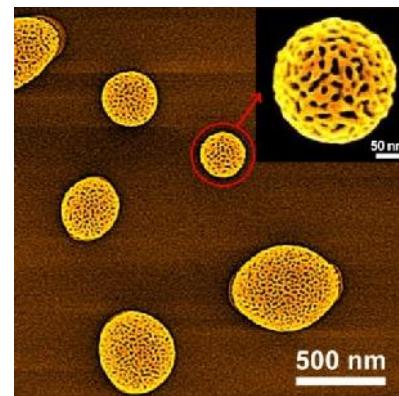
# Technische Universität Ilmenau

## *State: Thuringia*

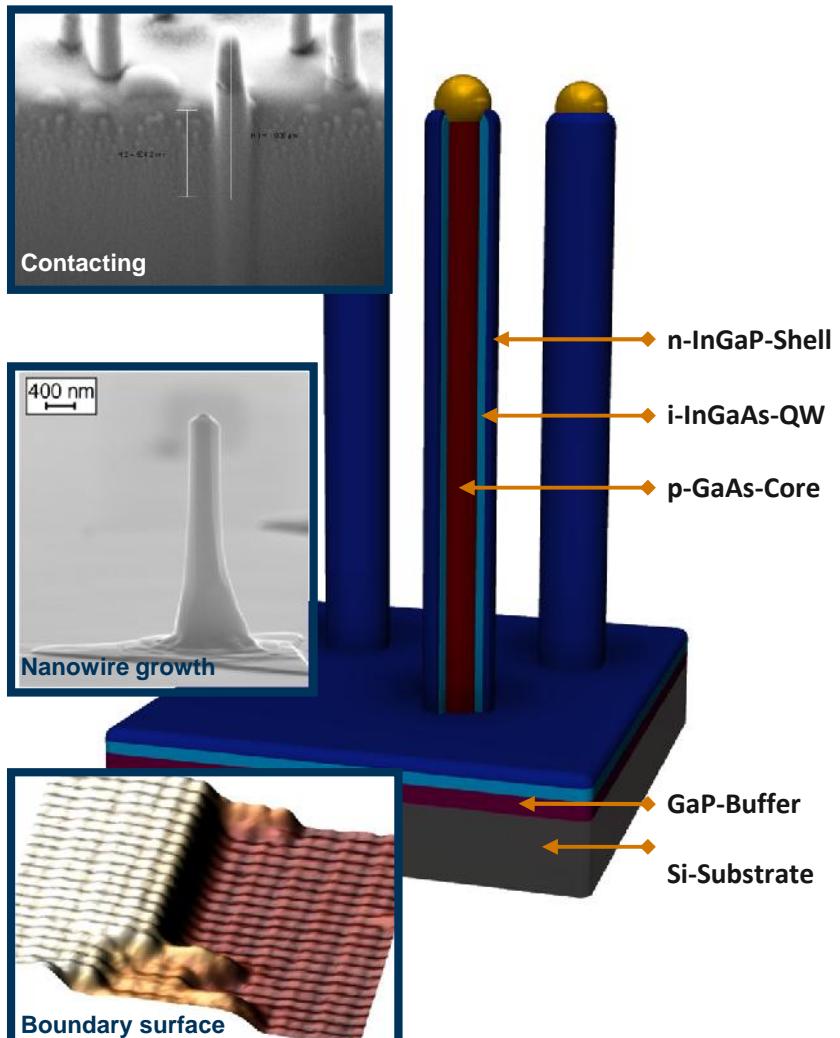


## Novel nanomaterials

- mesoporous gold nanoparticles with ultrahigh specific surface area and novel optical properties
- ordered arrays of single crystalline mesoporous Si nanopillars as functional materials
- Novel core/shell nanocomposites as functional materials ( $\text{TiO}_2$ ,  $\text{ZnO}$ )



# High efficiency solar cells



## Scope:

- Integration of III-V materials on Si technology
- Growth of III-V based radial nanowire structures for photovoltaic applications
- Evaluation of quantum well structures as light absorber in photovoltaic devices

## Tasks:

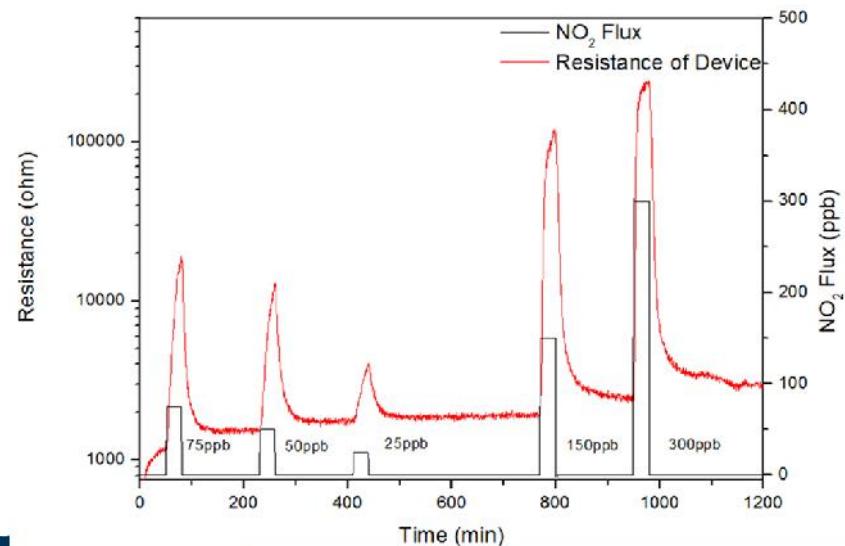
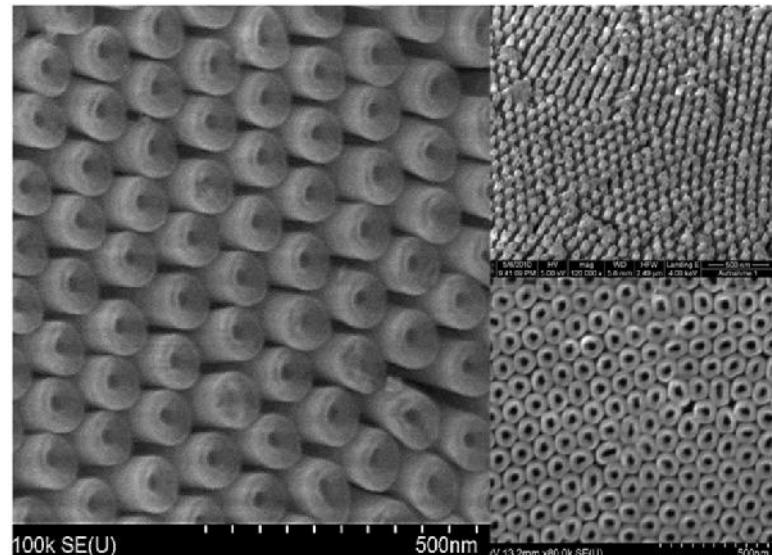
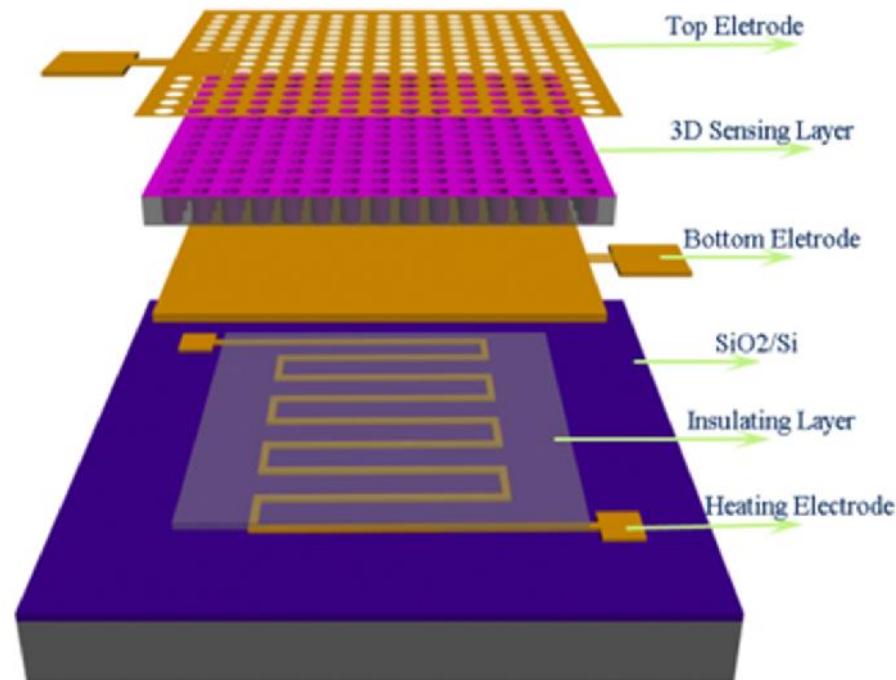
- In-situ analysis and UHV-characterization of MOVPE-prepared surfaces (XPS, LEED, FTIR, STM, etc.)
- Contacting of nanowire based devices with TCOs by MOCVD-growth

## Funded by:

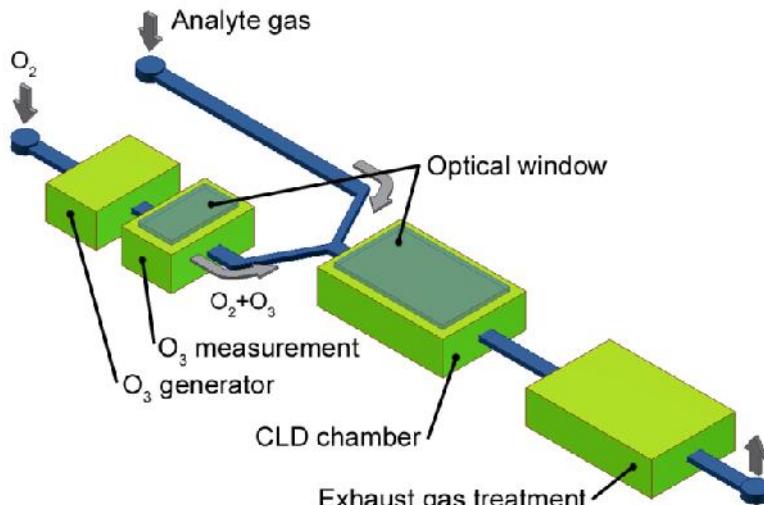


# Gas sensor based on 3D-nanoarchitectures

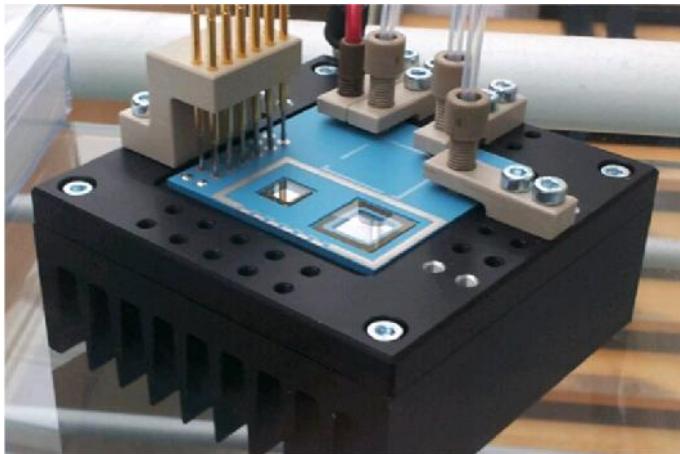
- 3D ZnO nanotube-array gas sensor realized on anodic alumina template by ALD
- sensitivity 25 ppb NO<sub>2</sub>



# NO-Sensor based on Chemiluminescent Reaction



System concept



System demonstrator

## Scope:

- Measurement of Nitrogen Monoxide Levels in Gas Flows with a Micro Total Analytical System ( $\mu$ TAS) based on LTCC

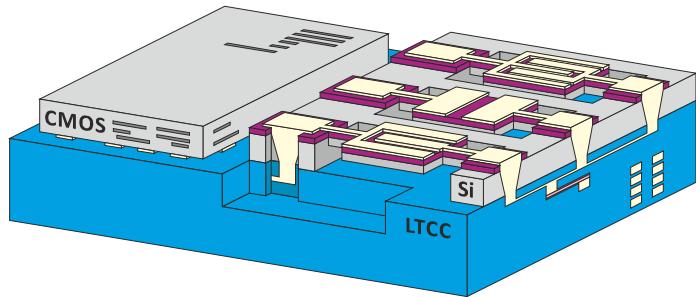
## Tasks:

LTCC-integration of:

- Micro-fluidic structures (in- and outlets, channels, chambers, gas mixing)
- Optical transparent encapsulation
- Passive electrical components
- Ozone generating structure
- Exhaust gas treatment

# Electro-Mechanical-Integration of Complex RF Circuits

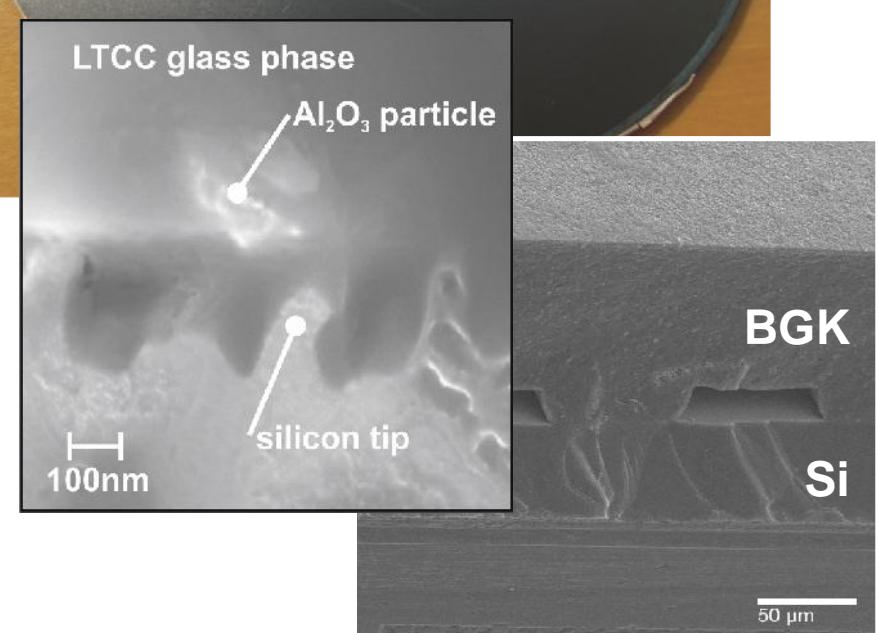
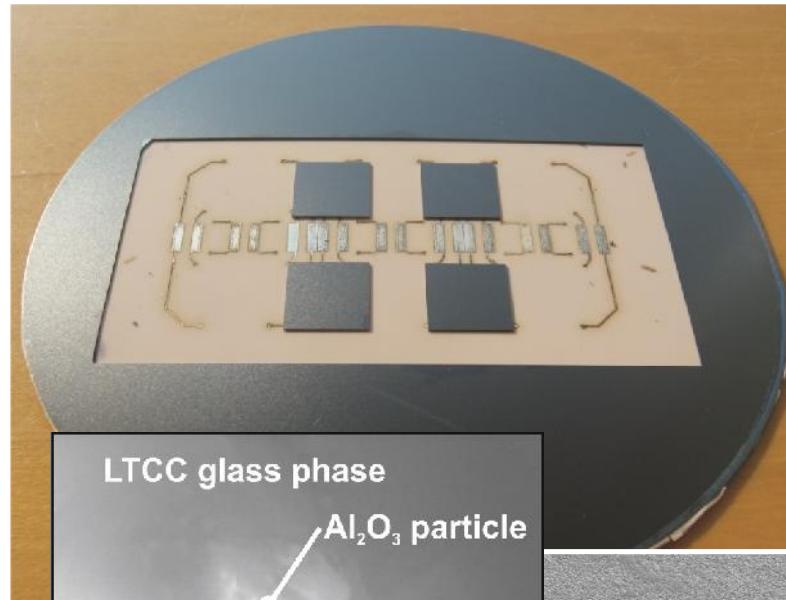
**Silicon RF MEMS + CMOS  
Actives + Passives**



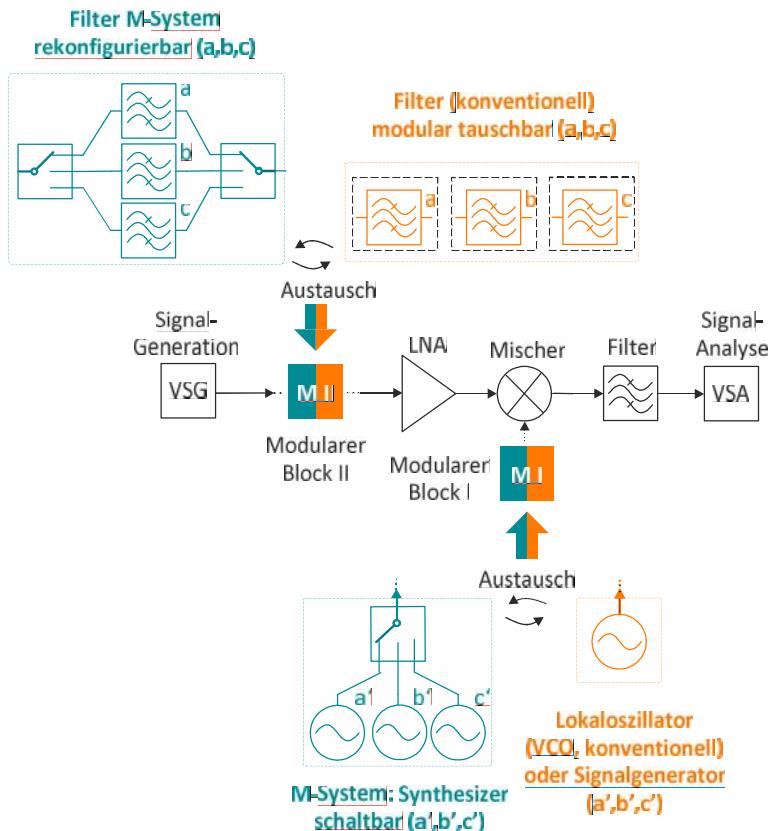
**on Ceramics**

**SiCer Compound  
Substrate Technology**

- Complex, functionalized SiCer-substrate with integrated and external RF-devices
- Integrated RF-suitable housing



# Project MUSIK (2012-2015/2018)



Sketch of envisioned RF-MEMS frontend demonstrator



Friedrich-Alexander-Universität  
Erlangen-Nürnberg



**X** FAB  
MIXED-SIGNAL FOUNDRY EXPERTS

**cadence**  
**COVENTOR**  
WHAT'S NEXT. AND NEXT. AND NEXT.

Contributing and associated partners

## Scope:

- Combine and merge microelectronics and micro-electromechanical worlds to establish “RF mechatronics”, employing unique hybrid substrate SiCer

## Tasks:

- Scientific co-ordination
- Monitor and supplement 7 workpackages
- Joint research and education activities
- Industrial interfaces

## Operating units:

- RF&Microwave Research Lab
- Electronics Technology
- Micromechanical Systems
- Electronic Circuits and Systems

**DFG** Deutsche  
Forschungsgemeinschaft

## Funded by:

- Research Unit (Forschergruppe)

# Project OK-Tech (2012-2013)



Digitally controllable switch-matrix circuit board



Satellite payload  
and rocket launch



I  
M  
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T  
  
TUHH

Tekhnische Universität Hamburg-Harburg



ASTRIUM  
AN EADS COMPANY

Astro-  
und Feinwerktechnik  
Adlershof GmbH

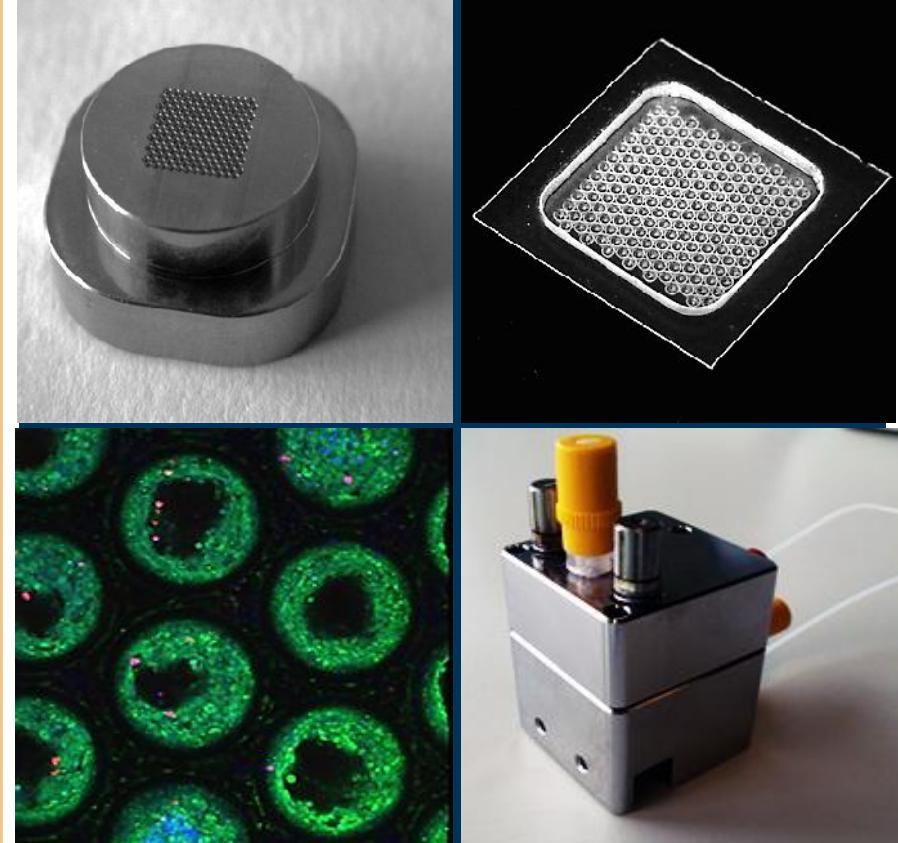


# Engineering of 3D cell cultivation systems

- Highly reproducible processing of 3D cell culture scaffolds
- Biofunctionalization of polymers
- Design and realization of microbioreactor systems and related microfluidic 3D cell culture equipment
- 3D sensors for 3D cell cultivation

## In-house biological application

- Qualification and characterization of 3D cell culture of hepatocytes, neuronal and stem cells

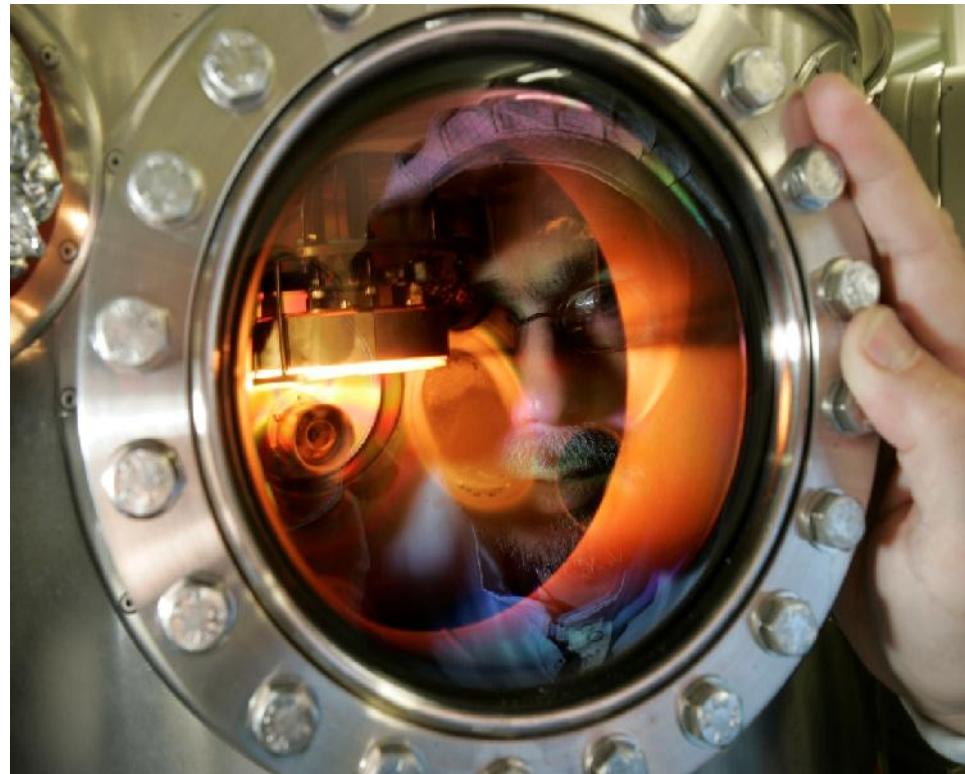


# Core facility: Center for Micro- and Nanotechnologies



# Materials in focus

- **Silizium** (*Poly-Si, SiO<sub>2</sub>, Si<sub>3</sub>N<sub>4</sub>*)
- **Metal carbides** (*SiC, WC*)
- **Metal nitrides** (*GaN, AlN*)
- **Metal oxides** (*ZnO, TiO<sub>2</sub>*)
- **Arsenides/Phosphides**
- **Metals** (*Ni, Pt, Cr, Au, Al, Cu*)
- **Ceramics** (*LTCC, Al<sub>2</sub>O<sub>3</sub>*)
- **Polymeres** (*P3HT, PEDOT*)
- **Glasses**



# Master Program Overview

## Master Micro- and Nanotechnologies (2016)

Modul / Fach	1. FS				2. FS				3. FS				4. FS				Abschluss	LP	Details
	V	Ü	P	V	V	Ü	P	V	V	Ü	P	V	V	Ü	P				
<b>Electronics Technology 1</b>																<b>MP</b>	<b>6</b>		
Electronics Technology 1	2	2	1													mPL 30 min	6		
<b>Semiconductor devices 1</b>																<b>MP</b>	<b>5</b>		
Semiconductor devices 1	2	2	0													mPL 30 min	5		
<b>Materials of Micro- and Nanotechnologies</b>																<b>MP</b>	<b>5</b>		
Materials of Micro- and Nanotechnologies	2	2	0													sPL 90 min	5		
<b>Nanodiagnostics</b>																<b>MP</b>	<b>5</b>		
Nanodiagnostics - Seminar and Practical course	0	1	1													SL	2		
Spectroscopic methods	2	0	0													mPL 30 min	3		
<b>Nanotechnology</b>																<b>MP</b>	<b>5</b>		
Nanotechnology	2	2	0													mPL 30 min	5		
<b>Micro Technologies 2</b>																<b>MP</b>	<b>5</b>		
Mikrotechnologie 2					2	1	1									mPL 30 min	5		
<b>Laboratory for Materials &amp; Micro/Nanofabrication</b>																<b>5</b>			
Laboratory for Nanomaterials					0	0	1									SL	2		
Micro/Nanofabrication Laboratory					0	0	2									SL	3		

Modul / Fach	1. FS	2. FS	3. FS	4. FS	Abschluss	LP	Details					
	V	Ü	P	V	Ü	P	V	Ü	P			
<b>Introduction to Project work / Soft skills</b>								<b>MP</b>	<b>9</b>			
Introduction to advanced research		2	0	0						aPL 60 min	3	
Introduction to scientific work		1	0	0						SL	2	
<b>Soft skills (Choice from the non-technical subject catalogue of the TU Ilmenau)</b>									<b>4</b>			
<b>Project with seminar</b>								<b>MP</b>	<b>10</b>			
Project with seminar					300h			PL 300 Stunden	10			
<b>Advanced Studies (Choice of subjects according to the actual catalogue)</b>								<b>MP</b>	<b>30</b>			
Advanced Packaging and Assembly Technology		2	2	0				mPL 30 min	5			
MEMS (Micro Electro Mechanical Systems)		2	1	0				sPL 120 min	4			
Material states and material analysis		2	1	1				PL	5			
Micro- and nanosystems technology 2		2	2	0				mPL 30 min	5			
Micro and nano sensor technology		2	2	0				mPL 30 min	5			
Micro and semiconductor technology 2		2	2	0				mPL 30 min	5			
Micro sensor technology		2	0	0				mPL 30 min	3			
Nanoelectronics		3	1	0				mPL 30 min	5			
Nanostructure physics		2	1	0				mPL	4			
Semiconductor devices 2		2	2	0				mPL 30 min	5			
3D material analysis				2	2	0		mPL 30 min	5			
Design von Mikrosystemen				2	1	0		mPL 30 min	4			
Functional materials				2	2	0		sPL 90 min	5			
Functional peripherics				2	1	1		mPL 30 min	4			
Ghz- and Thz- electronics				2	2	0		mPL 30 min	5			
Microactuators				2	0	0		mPL 30 min	3			
Thin films and surfaces				2	0	0		sPL 90 min	3			